

Abstract

A carrier device is described for magnetizable substrates, such as stainless steel substrates, which is suitable for processing thin-film substrates in particular. For this purpose, the described carrier device includes at least one magnetized base element (1) having at least one receptacle (7) for a substrate (2).

10 (Figure 1)

List of reference numerals

- 1 base element/base metal sheet
- 2 substrate
- 3 diaphragm
- 4 collar
- 5 substrate surface
- 6 substrate foot
- 7 receptacle/drilled hole
- 8 cover sheet (Figure 3)
- 9 stamped hole/through opening
- 10 cover sheet (Figure 4)
- 11 drilled hole
- 12 spacer sheet
- 13 shadow mask
- 14 pressure sheet